Wednesday, July 4th

08:30 - 09:00			**Registration**
09:00 - 09:20			**Opening (Gastón García, ALBA)**
In-situ metrology (Chair.: Kawal Sawhney)			
09:20 - 09:50	Simon Rutishauser	PSI	*In-situ optics metrology and wavefront diagnostics on synchrotrons and XFELs using X-ray grating interferometry* **(invited)**
09:50 - 10:10	John P. Sutter	Diamond	*Measurement and analysis of X-ray mirror slope errors under beamline operating conditions*
10:10 - 10:30	Marion Kuhlmann	DESY	*Hartmann Wavefront Measurements at the EUV-FEL FLASH*
10:30 - 10:50	Takashi Kimura	Osaka Univ.	*Development of wavefront characterization method for nearly diffraction-limited focused hard X-ray nanobeam.*
10:50 - 11:10	Hongchang Wang	Diamond	*At-wavelength metrology using Moiré Fringe analysis method based on two dimensional grating interferometer*
11:10 - 11:50			**Coffee break**
Ex-situ metrology I: interferometry (Chair.: Frank Siewert)			
11:50 - 12:10	François Polack	Soleil	*Determination and compensation of the "reference surface" from redundant sets of surface measurements*
12:10 - 12:30	Muriel Thomasset	Soleil	*A new Phase-shift Microscope Designed for High Accuracy Stitching Interferometry*
12:30 - 12:50	Hirokatsu Yumoto	Spring-8	*Absolute calibration of optical flats using the three-flat test at SPring-8*
12:50 - 13:10	Valeriy V. Yashchuk	ALS	*Ex situ metrology of x-ray diffraction gratings*
13:10 - 14:30			**Lunch**
x-ray optical systems (Chair.: Valeriy Yashchuk)			
14:30 - 15:00	Brian Ramsey	**NASA**	*Optics Requirements for X-Ray Astronomy and developments at the Marshall Space Flight Center* **(invited)**
15:00 - 15:20	Jens Viefhaus	Desy	*The Variable Polarization XUV beamline P04 at PETRA III: Optics, Mechanics and their Performance*
15:20 - 15:40	Haruhiko Ohashi	Spring-8	*Beamline optics for X-ray Free Electron Laser of SACLA*
15:40 - 16:20			**Coffee break**
16:20 - 16:40	Kazuto Yamauchi	Osaka Univ.	*Hard X-ray nanofocusing and wavefront diagnosis*
16:40 - 17:00	Jean-Sébastien Micha	ESRF	*Thermal Bump Removal of a Monochromator Crystal under X-ray load by optimising its shape*
17:00 - 17:20	Daniele La Civita	XFEL	*Soft X-ray monochromator for SASE3 beamline at European XFEL*

Thursday, July 5th

Beamline design and simulation (Chair.: Daniele Cocco)

09:00 - 09:30	Jacek Krzywinski	SLAC	*Beam Propagation Methods in X-ray optics simulations* **(invited)**
09:30 - 09:50	Cristian Svetina	Elettra	*A beam shaping active optics system for FERMI@Elettra FEL*
09:50 - 10:10	Konstantin Kaznatcheev	BNL	*Novel appaoches to SR beamline design*
10:10 - 10:30	Daniele Spiga	INAF BRERA	*X-ray beam-shaping via deformable mirrors: analytical computation of the required mirror profile*
10:30 - 10:50	Lorenzo Raimondi	Elettra	*Microfocusing of the FERMI@Elettra FEL beam with a K-B active optics system: spot size predictions by application of the RS-Code*
10:50 - 11:30			**Coffee Break**

Fabrication I: Multilayer Optics (Chair.: Mourad Idir)

11:30 - 11:50	Alexander Rack	ESRF	*Modifications of coherent hard X-rays beams induced by reflection on multilayer mirrors*
11:50 - 12:10	Monica Fernández Perea	LLNL	*Ultra-short-period WC/SiC multilayer coatings for x-ray applications*
12:10 - 12:30	Bianca Salmaso	INAF.BRERA	*X-ray scattering of periodic and graded multilayer: comparison of experiments to simulation from surface microroughness characterization*
12:30 - 12:50	Michael Stoermer	H.-Z. Geesthacht	*Investigations of the coating properties of x-ray optics for advanced research light sources in the soft x-ray domain*
12:50 - 14:10			**Lunch**
14:10 - 15:10			**Bus to ALBA**

Ex-situ metrology II: slope measuring instruments* (Chair.: Amparo Vivo)

15:10 - 15:30	Shinan Qian	BNL	*Advance in nano-accuracy surface profiler (NSP) and preliminary test*
15:30 - 15:50	Uwe Flechsig	SLS	*The upgraded LTP-V @ SLS*
15:50 - 16:10	Josep Nicolas	ALBA	*Characterization of the error budget for the ALBA-NOM*
16:10 - 16:30	Lahsen Assoufid	APS	*Development of a high-performance gantry system for a new generation of optical slope measuring profilers*
16:30 - 16:50	Mourad Idir	BNL	*X-ray mirror metrology using SCOTS: Software Configurable Optical Test System*
16:50 - 18:20			**Alba Tour**
18:20 - 19:20			**Bus to the Palau de la Música**
19:20 - 20:40			**Visit to the Palau de la Música**
20:40 - 23:40			**Dinner at the Mirador del Palau**

* This session will take place at the ALBA auditorium

Friday, July 6th

Ex-situ metrology III: slope measuring instruments (Chair.: Lahsen Assoufid)			
09:00 - 09:20	Oliver Kranz	PTB	*Ray-tracing simulation of autocollimators for deflectometric form measurement*
09:20 - 09:40	Jun Qian	APS	*Characterization of super-flat and curved mirrors with the new APS high resolution slope measuring profiler*
09:40 - 10:00	Frank Siewert	HZB-Berlin	*Investigations on the Performance of Autocollimator-based Slope Measuring Profilers*
10:00 - 10:20	Amparo Vivo	ESRF	*LTP Measurement of flat mirrors*
10:20 - 10:40	Michael Schultz	PTB	*High accuracy flatness metrology within the European Metrology Research Programme*
10:40 - 11:20			**Coffee Break**
Mirror manufacturing II: (Chair.: Kazuto Yamauchi)			
11:20 - 11:50	Simon G. Alcock	Diamond	*Bimorph mirrors: the good, the bad, and the ugly* **(invited)**
11:50 - 12:10	Hiroki Nakamori	Osaka Univ.	*Development of an Ultra-Precise Deformable Mirror for X-ray Focusing*
12:10 - 12:30	Iulian Preda	ESRF	*Ion beam etching of a flat silicon mirror surface: a study of the shape error evolution*
12:30 - 12:50	Akihiko Ueda	JTEC Corp.	*Fabrication of OSAKA MIRROR for Synchrotron Application*
12:50 - 14:10			**Lunch**
14:10 - 14:30			**Final remarks**
14:30 - 14:50			**Closing**